

Engineering Metrology By I C Gupta

Optical methods, stimulated by the advent of inexpensive and reliable lasers, are assuming an increasingly important role in the field of engineering metrology. Requiring only a basic knowledge of optics, this text provides a compendium of practical information prepared by leaders in the field.

Metrology and Properties of Engineering Surfaces provides in a single volume a comprehensive and authoritative treatment of the crucial topics involved in the metrology and properties of engineering surfaces. The subject matter is a central issue in manufacturing technology, since the quality and reliability of manufactured components depend greatly upon the selection and qualities of the appropriate materials as ascertained through measurement. The book can in broad terms be split into two parts; the first deals with the metrology of engineering surfaces and covers the important issues relating to the measurement and characterization of surfaces in both two and three dimensions. This covers topics such as filtering, power spectral densities, autocorrelation functions and the use of Fractals in topography. A significant proportion is dedicated to the calibration of scanning probe microscopes using the latest techniques. The remainder of the book deals with the properties of engineering surfaces and covers a wide range of topics including hardness (measurement and relevance), surface damage and the machining of brittle surfaces, the characterization

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of automobile cylinder bores using different techniques including artificial neural networks and the design and use of polymer bearings in microelectromechanical devices. Edited by three practitioners with a wide knowledge of the subject and the community, Metrology and Properties of Engineering Surfaces brings together leading academics and practitioners in a comprehensive and insightful treatment of the subject. The book is an essential reference work both for researchers working and teaching in the technology and for industrial users who need to be aware of current developments of the technology and new areas of application.

With design of products changing frequently, and functional requirements becoming more demanding, batch production of high precision components has become a necessity. The advent of NC and CNC has enabled automation of batch manufacturing supported by computerisation of manufacturing systems. The book is a complete reference consisting of several technologies associated with modern automated manufacturing.

This book focuses on the fundamental phenomena at nanoscale. It covers synthesis, properties, characterization and computer modelling of nanomaterials, nanotechnologies, bionanotechnology, involving nanodevices. Further topics are imaging, measuring, modeling and manipulating of low dimensional matter at nanoscale. The topics covered in the book are of vital importance in a wide range of modern and emerging technologies employed or to be employed in most industries, communication, healthcare, energy, conservation, biology, medical science, food, environment, and education, and consequently have great impact on our society.

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Engineering Metrology and Measurements is a textbook designed for students of mechanical, production and allied disciplines to facilitate learning of various shop-floor measurement techniques and also understand the basics of mechanical measurements.

Metrology has grown significantly, especially in semiconductor manufacturing, and such growth necessitates increased expertise. Until now, this field has never had a book written from the perspective of an engineer in a modern IC manufacturing and development environment. The topics in this Tutorial Text range from metrology at its most basic level to future predictions and challenges, including measurement methods, industrial applications, fundamentals of traditional measurement system characterization and calibration, semiconductor-specific applications, optical metrology measurement techniques, charged particle measurement techniques, x-ray and in situ metrology, hybrid metrology, and mask making. The accompanying CD includes example spreadsheets of measurement uncertainty analysis—specifically, precision, matching, and relative accuracy.

New Scientist magazine was launched in 1956 "for all those men and women who are interested in scientific discovery, and in its industrial, commercial and social consequences". The brand's mission is no different today - for its consumers, New Scientist reports, explores

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and interprets the results of human endeavour set in the context of society and culture. Due to their speed, data density, and versatility, optical metrology tools play important roles in today's high-speed industrial manufacturing applications. Handbook of Optical Dimensional Metrology provides useful background information and practical examples to help readers understand and effectively use state-of-the-art optical metrology methods. The book first builds a foundation for evaluating optical measurement methods. It explores the many terms of optical metrology and compares it to other forms of metrology, such as mechanical gaging, highlighting the limitations and errors associated with each mode of measurement at a general level. This comparison is particularly helpful to current industry users who operate the most widely applied mechanical tools. The book then focuses on each application area of measurement, working down from large area to medium-sized to submicron measurements. It describes the measurement of large objects on the scale of buildings, the measurement of durable manufactured goods such as aircraft engines and appliances, and the measurement of fine features on the micron and nanometer scales. In each area, the book covers fast, coarse measures as well as the finest measurements possible. Best practices and practical examples for each technology aid readers in effectively using the methods. Requiring no prior expertise in optical dimensional metrology, this handbook helps engineers and quality specialists understand the capabilities and limitations of optical metrology methods. It also shows them how to successfully apply optical metrology to a vast array of current engineering and scientific problems.

Here is a comprehensive practical guide to entire wafer fabrication process from A to Z. Written by a practicing process engineer with years of experience, this book provides a

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thorough introduction to the complex field of IC manufacturing, including wafer area layout and design, yield optimization, just-in-time management systems, statistical quality control, fabrication equipment and its setup, and cleanroom techniques. In addition, it contains a wealth of information on common process problems: How to detect them, how to confirm them, and how to solve them. Whether you are a new engineer or technician just entering the field, a fabrication manager looking for ways to improve quality and production, or someone who would just like to know more about IC manufacturing, this is the book you're looking for. Provides a readable, practical overview of the entire wafer fabrication process for new engineers and those just entering this complex field Enables engineers and managers to improve production, raise quality levels, and solve problems that commonly occur in the fabrication process Presents the latest techniques and gives special attention to Japanese IC manufacturing techniques, showing how they obtain outstanding quality Metrology has grown significantly, especially in semiconductor manufacturing, and such growth necessitates increased expertise. Until now, this field has never had book written from the perspective of an engineer in a modern IC manufacturing and development environment. The topics in this Tutorial Text range from metrology at its most basic level to future predictions and challenges, including measurement methods, industrial applications, fundamentals of traditional measurement system characterization and calibration, measurement system characterization and calibration,

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semiconductor-specific applications, optical metrology measurement techniques, charged particle measurement techniques, x-ray and in situ metrology, hybrid metrology, and mask making. Includes example spreadsheets of measurement uncertainty analysis--specifically, precision, matching, and relative accuracy.

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